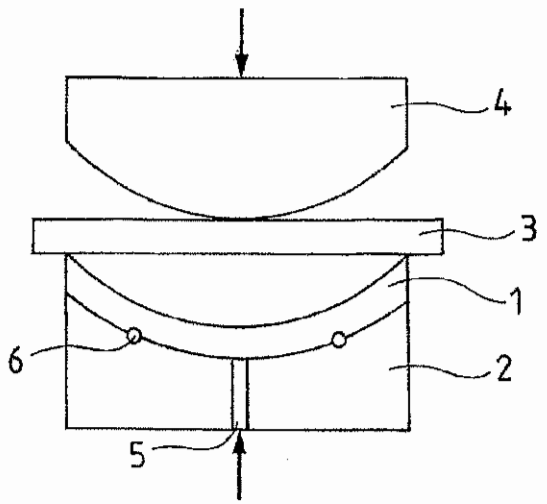


Fig. 1

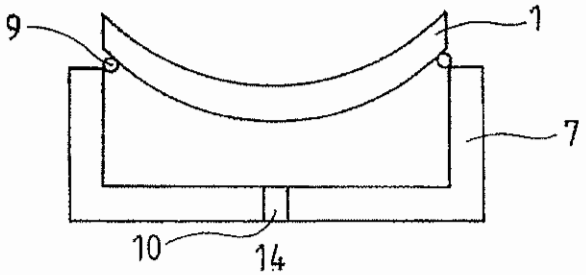


Fig. 2

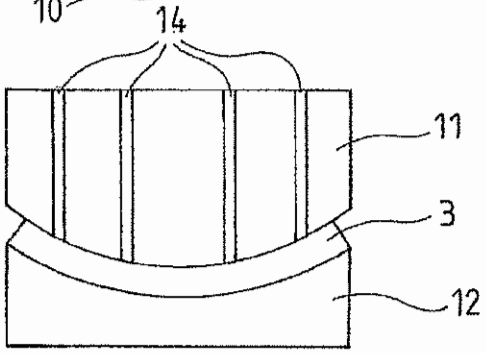


Fig. 3

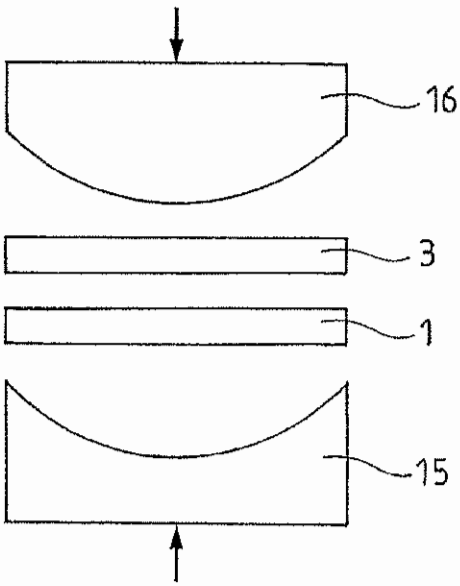


Fig. 4

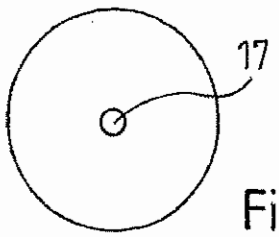


Fig. 5A

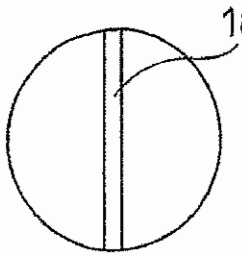


Fig. 5B

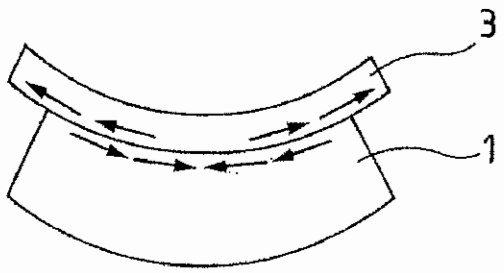


Fig. 6A

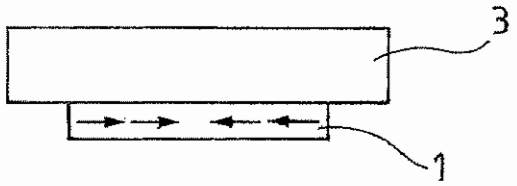


Fig. 6B

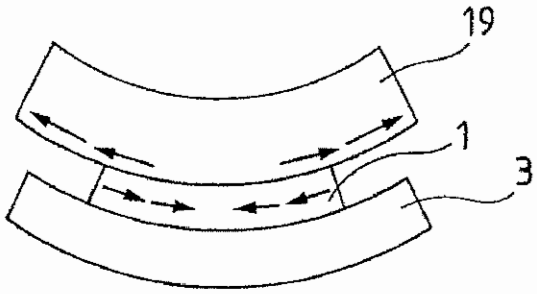


Fig. 6C

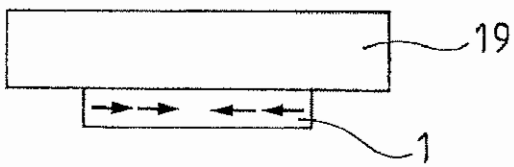


Fig. 6D

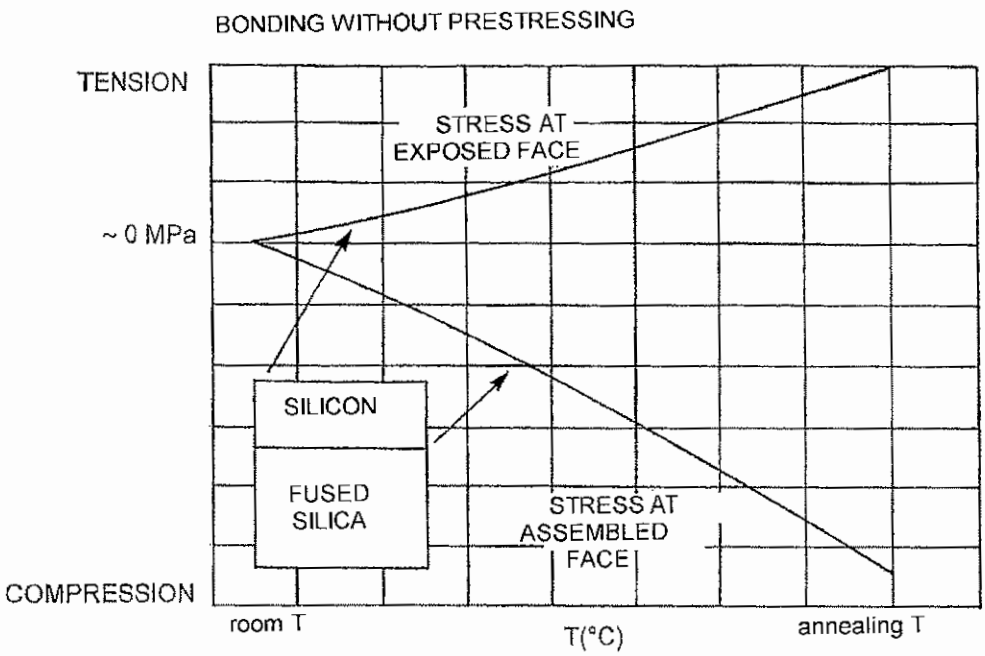

BONDING WITHOUT PRESTRESSING
TENSION
~ 0 MPa
COMPRESSION
STRESS AT EXPOSED FACE
SILICON
FUSED SILICA
STRESS AT ASSEMBLED FACE
room T
T(°C)
annealing T

Fig. 7A

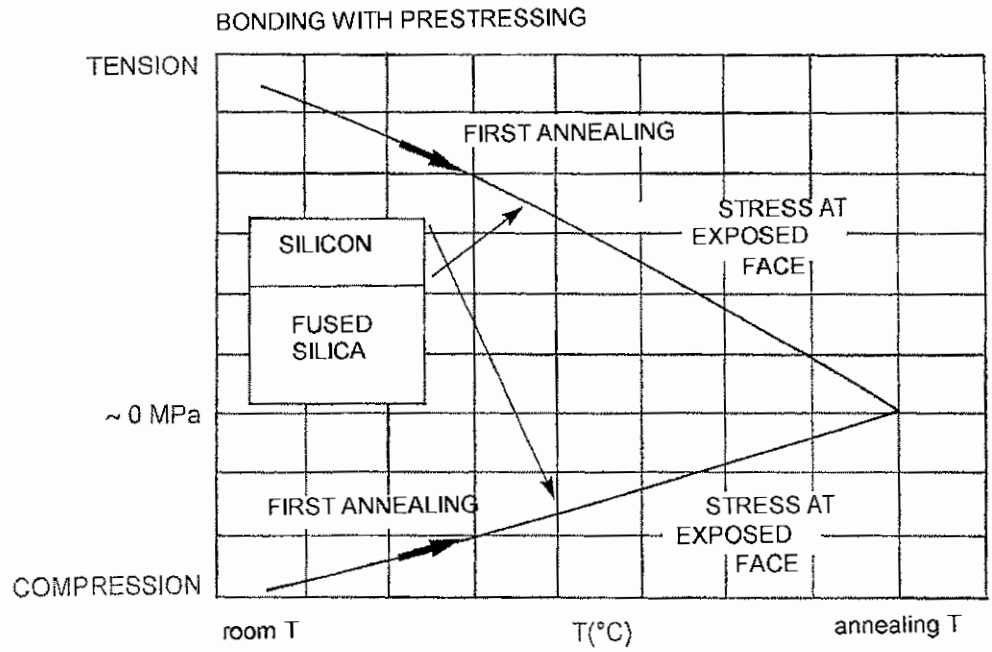

BONDING WITH PRESTRESSING
TENSION
~ 0 MPa
COMPRESSION
FIRST ANNEALING
STRESS AT EXPOSED FACE
SILICON
FUSED SILICA
FIRST ANNEALING
STRESS AT EXPOSED FACE
room T
T(°C)
annealing T

Fig. 7B

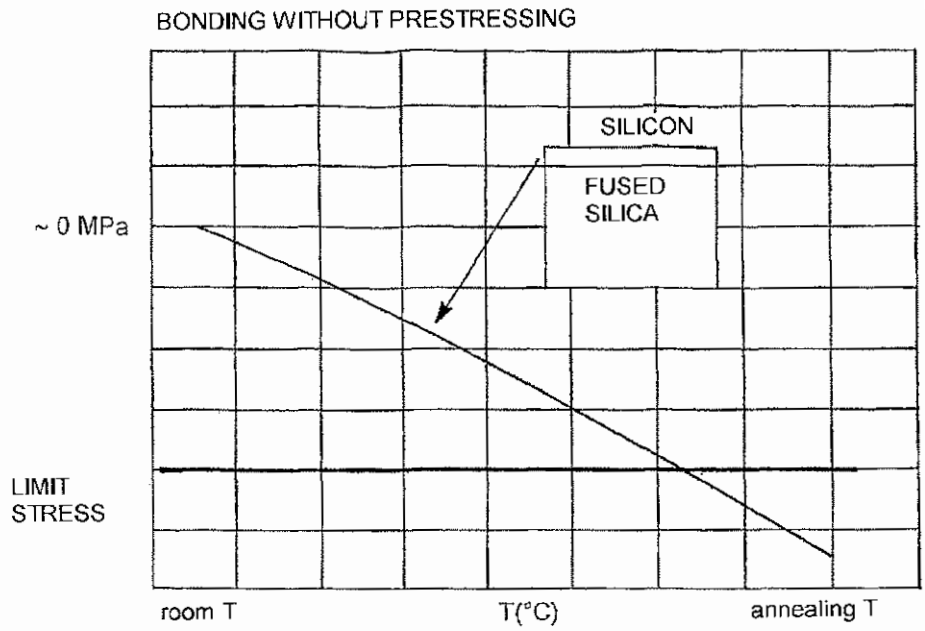

BONDING WITHOUT PRESTRESSING
SILICON
FUSED SILICA
~ 0 MPa
LIMIT STRESS
room T
T(°C)
annealing T

Fig. 8A

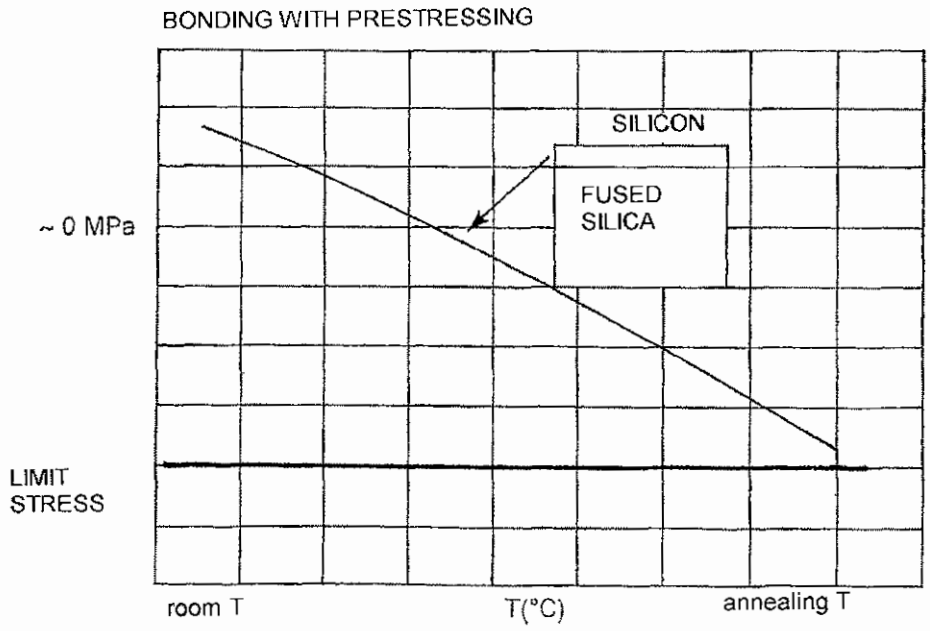

BONDING WITH PRESTRESSING
SILICON
FUSED SILICA
~ 0 MPa
LIMIT STRESS
room T
T(°C)
annealing T

Fig. 8B

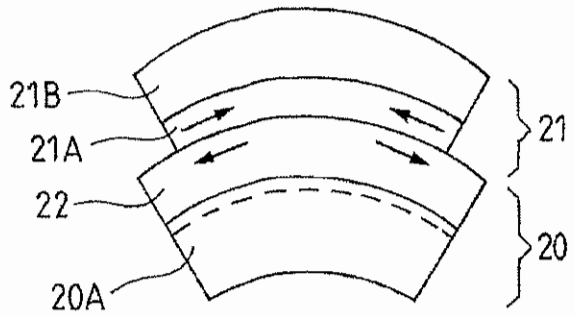


Fig. 9A

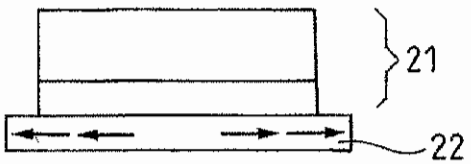


Fig. 9B

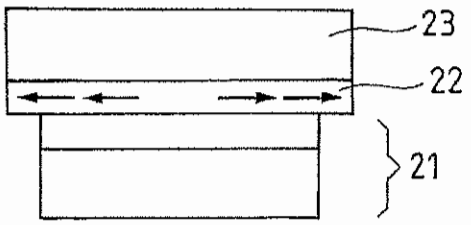


Fig. 9C

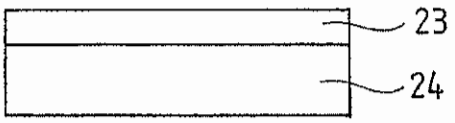


Fig. 9D

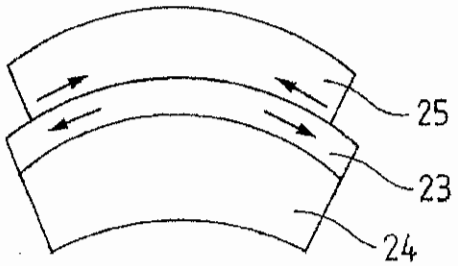


Fig. 9E

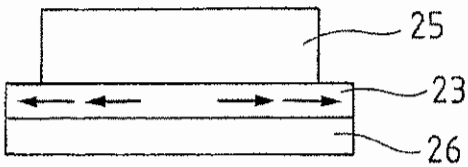


Fig. 9F

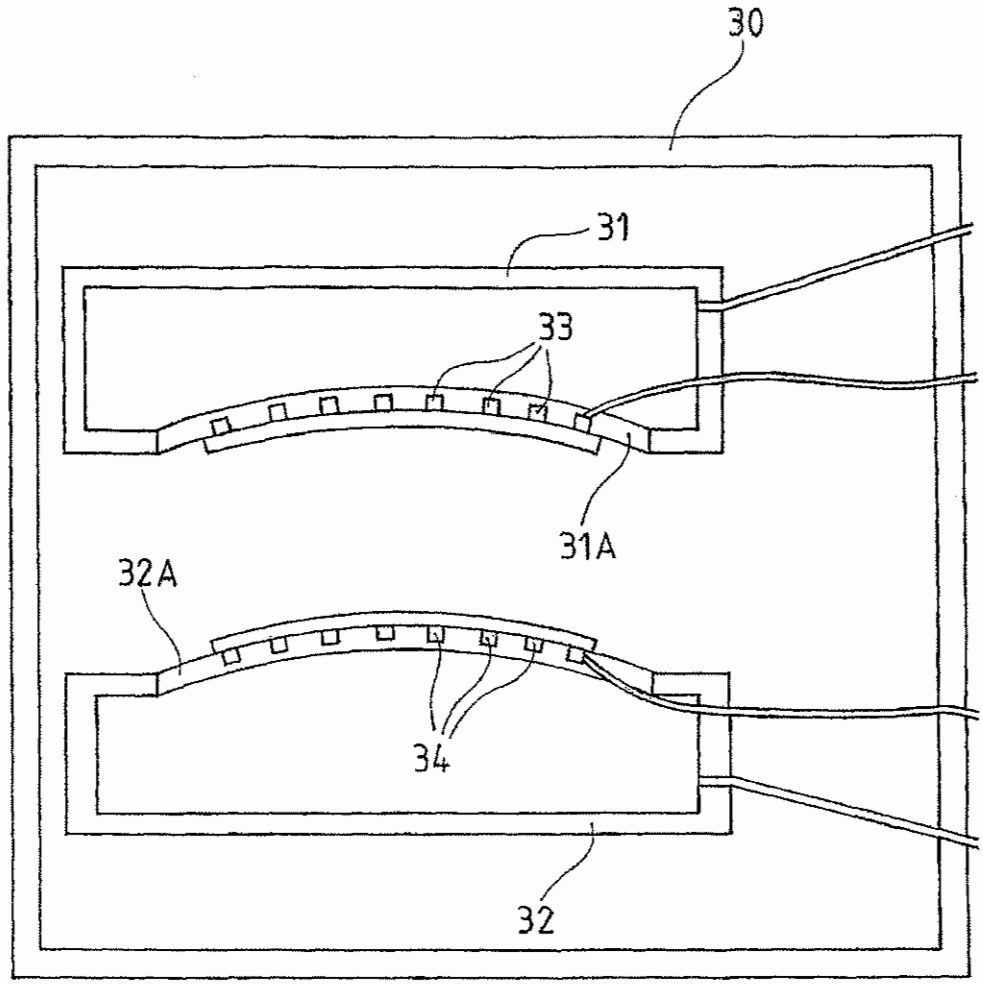


Fig. 10